

L Number	Hits	Search Text	DB	Time stamp
1	1490	(photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)	JPO; DERWENT	2003/03/17 18:38
4	4	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 (horizontal horizontal))	JPO; DERWENT	2003/03/17 19:19
7	0	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 ((surface substrate) near3 ("not" adj expos\$3)))	JPO; DERWENT	2003/03/17 19:19
10	296	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) same (system apparatus)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:37
24	0	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) same (system apparatus)) and @rlad<19960422	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:38
17	253	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) same (system apparatus)) and @ad<19960422	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:37
31	3847	(photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:39
38	4	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 (horizontal horizontal))	JPO; DERWENT	2003/03/17 18:40
41	0	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 ((surface substrate) near3 ("not" adj expos\$3)))	JPO; DERWENT	2003/03/17 18:40
51	0	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 ((surface substrate) near3 ("not" adj expos\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:40
44	22	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 (horizontal horizontal))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 19:20
58	1294	sandhu.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 19:09
65	2	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and sandhu.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 19:10
75	584	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 (side))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 19:21
72	36	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 (side))	JPO; DERWENT	2003/03/17 19:21

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10	296	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) same (system apparatus)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:37
24	0	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) same (system apparatus)) and @rlad<19960422	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:38
17	253	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) same (system apparatus)) and @ad<19960422	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:37
31	3847	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 18:39
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44	22	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and ((light\$3 source lamp illuminat\$3) near6 (horizontal horizontal))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 19:09
58	1294	sandhu.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 19:09
65	2	((photo uv optical) near5 ((chemical adj2 vapor adj2 deposit\$3) CVD)) and sandhu.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/17 19:10